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| APPLICATION NO.                                | FILING DATE          | FIRST NAMED INVENTOR | ATTORNEY DOCKET NO.     | CONFIRMATION NO. |
|--|----------------------|----------------------|-------------------------|------------------|
| 10/046,443                                     | 11/07/2001           | J. Craig Raese       | 10011455-1              | 4173             |
| 75   | 590 09/20/2005       |                      | EXAM                    | INER             |
| HEWLETT-PACKARD COMPANY                        |                      | GIESY, ADAM          |                         |                  |
| Intellectual Pro                               | perty Administration |                      |                         |                  |
| P.O. Box 272400<br>Fort Collins, CO 80527-2400 |                      | ART UNIT             | PAPER NUMBER            |                  |
|  |                      | 2651                 |                         |                  |
|  |                      |                      | DATE MAILED: 09/20/2005 |                  |

Please find below and/or attached an Office communication concerning this application or proceeding.

|  | Application No.  | Amelia autini  |  |  |
|--|--|--|--|--|
|  |  | Applicant(s)   |  |  |
| Office Action Summer   | 10/046,443   | RAESE, J. CRAIG  |  |  |
| Office Action Summary  | Examiner   | Art Unit   |  |  |
|  | Adam R. Giesy  | 2651   |  |  |
| The MAILING DATE of this communication apportunity  Period for Reply   | ears on the cover sheet with the c   | orrespondence address  |  |  |
| A SHORTENED STATUTORY PERIOD FOR REPLY WHICHEVER IS LONGER, FROM THE MAILING DA  - Extensions of time may be available under the provisions of 37 CFR 1.13 after SIX (6) MONTHS from the mailing date of this communication.  - If NO period for reply is specified above, the maximum statutory period w  - Failure to reply within the set or extended period for reply will, by statute, Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b). | ATE OF THIS COMMUNICATION  16(a). In no event, however, may a reply be time  11 apply and will expire SIX (6) MONTHS from the cause the application to become ABANDONE | l.<br>ely filed<br>the mailing date of this communication.<br>D (35 U.S.C. § 133). |  |  |
| Status   |  |  |  |  |
| 1)⊠ Responsive to communication(s) filed on <u>07 Ju</u>   | ilv 2005   |  |  |  |
|  | action is non-final.   |  |  |  |
| 3) Since this application is in condition for allowan  |  | secution as to the merits is   |  |  |
| closed in accordance with the practice under E   |  |  |  |  |
|  | ,  |  |  |  |
| Disposition of Claims  |  |  |  |  |
| 4)⊠ Claim(s) <u>1-22</u> is/are pending in the application.  |  |  |  |  |
| 4a) Of the above claim(s) is/are withdraw  | vn from consideration.   |  |  |  |
| 5)⊠ Claim(s) <u>13 and 14</u> is/are allowed.  |  | •  |  |  |
| 6)⊠ Claim(s) <u>1-12 and 15-22</u> is/are rejected.  |  |  |  |  |
| 7) Claim(s) is/are objected to.  |  | •  |  |  |
| 8) Claim(s) are subject to restriction and/or  | r election requirement.  | ·  |  |  |
| Application Papers   | •  |  |  |  |
| 9) The specification is objected to by the Examine   | r  |  |  |  |
| 10)⊠ The drawing(s) filed on <u>07 November 2001</u> is/ai   |  | ed to by the Examiner.   |  |  |
| •  |  |  |  |  |
| Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).  Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d).  |  |  |  |  |
| 11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.   |  |  |  |  |
| ,—   |  |  |  |  |
| Priority under 35 U.S.C. § 119   |  |  |  |  |
| 12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).  a) All b) Some * c) None of:  1. Certified copies of the priority documents have been received.   |  |  |  |  |
| 2. Certified copies of the priority documents have been received in Application No   |  |  |  |  |
| <ol> <li>Copies of the certified copies of the prior<br/>application from the International Bureau</li> </ol>  |  | ed in this National Stage  |  |  |
| * See the attached detailed Office action for a list   |  | ed   |  |  |
|  |  |  |  |  |
| ·  |  |  |  |  |
| Ami abassanta)   |  |  |  |  |
| Attrachment(s)  1) Notice of References Cited (PTO-892)  | 4) Interview Summary   | (PTO-413)  |  |  |
| 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) Paper No(s)/Mail Date.   |  |  |  |  |
| 3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08)  5) Notice of Informal Patent Application (PTO-152)   |  |  |  |  |
| Paper No(s)/Mail Date  | 6)   |  |  |  |

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### DETAILED ACTION

# Claim Objections

1. Claim 21 is objected to because of the following informalities:

It is unclear as to whether the limitation "further comprising using..." refers to the method or the storage medium. Examiner suggests rewording claim to read "...storage areas; and **the method** further comprising using...."

Appropriate correction is required.

2. In view of the objection above, claim 21 will be examined in light of the amendment suggested by the Examiners, above.

## Claim Rejections - 35 USC § 103

- 3. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
  - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 4. Claims 1-8, 10-12, 15-17, 21, and 22 are rejected under 35 U.S.C. 103(a) as being unpatentable over Naberhuis et al. (hereinafter Naberhuis US Pat. No. 6,643,248 B2) in view of Pfeiffer (hereinafter Pfeiffer '305 US Pat. No. 4,423,305).

Regarding claim 1, Naberhuis discloses a method for controlling the voltage on a lens of an electron emitting device, the method comprising: providing a storage medium having a storage area (see column 3, lines 46 and 47), a structural state of the storage area being alterable by a beam of electrons emitted by the electron emitting device to represent information stored in the storage area (column 3, line 56 thru column 4, line

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5); supplying an emitter voltage to an electron emitter in the electron emitting device, wherein a current amplitude is established (column 7, line 51 thru column 8, line 2). Naberhuis does not disclose supplying a non-inverted output voltage or providing an amplifier output voltage.

Pfeiffer '305 incorporates by reference, Pfeiffer et al. (Pfeiffer '271 – US Pat. No. 3,894,271).

Pfeiffer '305 discloses a method for controlling the voltage on a lens of an electron emitting device, comprising: supplying an emitter voltage to an electron emitter (see column 3, lines 39-46 – supplying a voltage to the source is inherent to the source, as the source is emitting electrons. Applying a voltage through the described filament to excite the electrons is a fundamental way to excite the electrons); sensing the emitter voltage on the electron emitter (sensing plates – column 5, lines 58-66); supplying a non-inverted input voltage to an amplifier that follows the emitter voltage (implemented in Pfeiffer '305, but shown in Pfeiffer '271 – for circuit, see Pfeiffer '271 - Figure 4, elements 34 and 43); and providing an amplifier output voltage from the amplifier to the lens, wherein the amplifier output voltage corresponds to the emitter voltage at the electron emitter (see column 6, lines 51-60).

It would have been obvious to one of ordinary skill in the art at the time the invention was made to combine the electron emitter storage device as disclosed by Naberhuis with the electron emitter as disclosed by Pfeiffer '305, the motivation being to create an electron emitter with greater aiming capability for use in recording on a storage medium.

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Regarding claim 2, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 1 as discussed in the claim 1 rejection above. Pfeiffer '305 further discloses that other lenses (column 4, lines 23-38) are driven in the emitting device based on the amplifier output voltage supplied by the amplifier (column 6, lines 51-60).

Regarding claim 3, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 1 as discussed in the claim 1 rejection above Naberhuis further discloses that the output voltage causes the lens to optimize the focal point of a beam emitted from the electron emitter relative to the storage area (column 3, line 56 thru column 4, line 5 – see also column 8, line 56 thru column 9, line 8).

Regarding claim 4, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 3 as discussed in the claim 3 rejection above. Pfeiffer '305 further discloses that amplifier output voltage is adjusted by varying the gain of the amplifier (see Pfeiffer '271 - Figure 4, element 43 – the gain of amplifier is determined by the input of element 34, and therefore the output is varied by the input).

Regarding claim 5, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 4 as discussed in the claim 4 rejection above. Pfeiffer '305 further discloses that the gain is varied by a variable resistor coupled to the amplifier (see 'potentiometer' – column 6, line 53).

Regarding claim 6, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 1 as discussed in the claim 1 rejection above. Pfeiffer '305 further discloses that the sensing is performed by a sensing diode (the sensing plate is acting as a sensor for

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the current/voltage of the beam from the emitter, and thusly is performing the same function).

Regarding claim 7, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 1 as discussed in the claim 1 rejection above. Pfeiffer '305 further discloses that the sensing is performed by an electric switch (the sensing plate is acting as a sensor for the current/voltage of the beam from the emitter, and thusly is functioning in the same fashion as an electric switch. See Pfeiffer '271 - Figure 2, elements 32, 34, and 35 - the electrons interact between layers 32 and 34 which are separated by an insulating layer 35, and thus the configuration acts as a switch).

Regarding claim 8, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 1 as discussed in the claim 1 rejection above. Pfeiffer '305 further discloses that the sensing is performed by one or more high-breakdown voltage MOS transistors (the sensing plate is acting as a sensor for the current/voltage of the beam from the emitter, and thusly is performing the same function).

Regarding claim 10, Naberhuis discloses a storage medium comprising: an electron emitter (see column 3, lines 45-55); a storage medium having a storage area (see column 3, lines 46 and 47), a structural state of the storage area being alterable by a beam of electrons emitted by the electron emitting device to represent information stored in the storage area (column 3, line 56 thru column 4, line 5); a lens to adjust the focal point of the beam of electrons emitted from the electron emitter (column 8, line 56 thru column 9, line 8). Naberhuis does not disclose a sensing switch or an amplifier coupled to the sensing switch.

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Pfeiffer '305 discloses an electron emitter with a sensing switch coupled to the electron emitter to sense voltage on the electron emitter (see 'sensing plate 36' – column 5, lines 58-66); an amplifier coupled to the sensing switch that follows the voltage on the electron emitter, wherein the sensing switch is coupled to an input of the amplifier and the output of the amplifier is coupled to the lens; and wherein the output of the amplifier drives the voltage on the lens (see Pfeiffer '271 - Figure 5 elements 34 and 37 as incorporated by reference).

It would have been obvious to one of ordinary skill in the art at the time the invention was made to combine the storage unit and electron emitter as disclosed by Naberhuis with the electron emitter as disclosed by Pfeiffer '305, the motivation being to create an electron emitter with greater aiming capability for use in recording on a storage medium.

Regarding claim 11, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 10 as discussed in the claim 10 rejection above. Pfeiffer '305 further discloses that a variable resistor is coupled to an input of the amplifier, wherein the gain of the amplifier is adjusted according to the variable resistor (see 'potentiometer' – column 6, line 53).

Regarding claim 12, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 10 as discussed in the claim 10 rejection above. Pfeiffer '305 further discloses that the sensing switch is a sensing diode (the sensing plate is acting as a sensor for the current/voltage of the beam from the emitter, and thusly is performing the same function).

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Regarding claim 15, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 10 as discussed in the claim 10 rejection above. Pfeiffer '305 further discloses that an emitter current switch (see column 4, lines 45-50); and a current control circuit (shown in Pfeiffer '271 - Figure 2, element 39) coupled to the sensing switch ('sensing plate 36' - column 5, lines 58-66), emitter current control switch (column 4, lines 45-50), and the variable resistor ('potentiometer 44' – column 6, line 52), wherein the current control circuit establishes the current amplitude supplied to the electron emitter (see column 4, lines 39-50).

Regarding claim 16, Naberhuis discloses an electron emitting storage device, comprising: emitter means for emitting electrons (see column 3, lines 45-55); storage means for storing information, the storage means exhibiting a structural state that is selectively alterable by electrons emitted by the emitter means (column 3, line 56 thru column 4, line 5); and lens means for focusing emitted electrons from the emitter means into an optimized focal point on the storage means (column 8, line 56 thru column 9, line 8). Naberhuis does not disclose the voltage sensor or an amplifier.

Pfeiffer '305 discloses an electron emitter, comprising: means for sensing voltage applied to the emitter means (sensing plates – column 5, lines 58-66); amplifier means for providing an output voltage to the lens means that is relative to the voltage applied to the emitter means (implemented in Pfeiffer '305, but shown in Pfeiffer '271, see Pfeiffer '271 - Figure 4, elements 34 and 43); and means for adjusting input voltage to the amplifier means so that the output voltage to the lens means changes (column 6, lines 51-60).

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It would have been obvious to one of ordinary skill in the art at the time the invention was made to combine the storage unit and electron emitter as disclosed by Naberhuis with the electron emitter as disclosed by Pfeiffer '305, the motivation being to create an electron emitter with greater aiming capability for use in recording on a storage medium.

Regarding claim 17, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 16 as discussed in the claim 16 rejection above. Pfeiffer '305 further discloses that means for controlling the current in the emitter means (aperture 27 – see column 5, lines 61-66); and switching means for activating the emitter means (shown in Pfeiffer '271, see Pfeiffer '271 - Figure 2, element 14).

Regarding claim 21, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 1 as discussed in the claim 1 rejection above Naberhuis further discloses that the storage medium has additional storage areas (see abstract); and the method further comprising using the emitting device to alter a structural state of at least one of the additional storage areas (column 3, line 56 thru column 4, line 5).

Regarding claim 22, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 21 as discussed in the claim 21 rejection above Naberhuis further discloses that the method further comprises moving the storage medium and the electron emitting device relative to each other such that the electron emitting device is aligned to alter a structural state of at least one of the additional storage areas (column 3, line 45 thru column 4, line 5).

5. Claims 9, and 18-20 are rejected under 35 U.S.C. 103(a) as being unpatentable over Naberhuis et al. (hereinafter Naberhuis – US Pat. No. 6,643,248 B2) in view of Pfeiffer (hereinafter Pfeiffer '305 - US Pat. No. 4,423,305) and further in view of Notte, IV (Notte – US Pat No. 6,515,287 B2).

Regarding claim 9, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 1 as discussed in the claim 1 rejection above. Neither Naberhuis nor Pfeiffer '305 disclose a non-inverting summer circuit.

Notte discloses a magnetic lens which can be used to alter the direction of a charged particle beam with an non-inverting op amp (Figure 5, element 108) that sums the emitter voltage (sensed from the magnetic field using elements 98 and 104) and the lens voltage (106).

It would have been obvious to one of ordinary skill in the art at the time the invention was made to combine the beam emitter and storage device as disclosed by the combination of Naberhuis and Pfeiffer '305 with the magnetic lens and amplifier circuit as disclosed Notte, the motivation being to more accurately control the direction of the electron beam on the storage area.

Regarding claim 18, Naberhuis and Pfeiffer '305 disclose all of the limitations of claim 16 as discussed in the claim 16 rejection above. Neither Naberhuis nor Pfeiffer '305 disclose a non-inverting amplifier.

Notte discloses a magnetic lens which can be used to alter the direction of a charged particle beam with an non-inverting op amp (Figure 5, element 108) that sums

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the emitter voltage (sensed from the magnetic field using elements 98 and 104) and the lens voltage (106).

It would have been obvious to one of ordinary skill in the art at the time the invention was made to combine the beam emitter and storage device as disclosed by the combination of Naberhuis and Pfeiffer '305 with the magnetic lens and amplifier circuit as disclosed Notte, the motivation being to more accurately control the direction of the electron beam on the storage area.

Regarding claim 19, Naberhuis discloses a method for controlling the voltage on a lens of an electron emitting device, the method comprising: supplying an emitter voltage to an electron emitter in the electron emitting device (column 7, line 51 thru column 8, line 2); and providing a storage medium having a storage area (see column 3, lines 46 and 47), a structural state of the storage area being alterable by a beam of electrons emitted by the electron emitting device to represent information stored in the storage area (column 3, line 56 thru column 4, line 5). Naberhuis does not disclose sensing the voltage or summing the sensed lens voltages.

Pfeiffer '305 discloses sensing the emitter voltage on the electron emitter (sensing plates – column 5, lines 58-66).

Notte discloses a magnetic lens which can be used to alter the direction of a charged particle beam in which the sensed voltage and the lens voltage are summed (see Figure 5, elements 98, 104, 106, and 108). The op amp cited above output this signal (see output of element 108).

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It would have been obvious to one of ordinary skill in the art at the time the invention was made to combine the beam emitter as disclosed by Naberhuis with the voltage sensing on the electron emitter as disclosed by Pfeiffer '305 and the magnetic lens and amplifier circuit as disclosed Notte, the motivation being in order to create a more accurate method of control while controlling the electron beam.

Regarding claim 20, Naberhuis, Pfeiffer '305, and Notte disclose all of the limitations of claim 19 as discussed in the claim 19 rejection above. Pfeiffer '305 further discloses driving other lenses (column 4, lines 23-38) in the emitting device based on the provided voltage output (column 6, lines 51-60).

# Allowable Subject Matter

6. Claims 13 and 14 are allowed for reasons cited in the previous Office Action, mailed on 4/4/2005.

### Conclusion

7. Applicant's amendment necessitated the new ground(s) of rejection presented in this Office action. Accordingly, **THIS ACTION IS MADE FINAL**. See MPEP § 706.07(a). Applicant is reminded of the extension of time policy as set forth in 37 CFR 1.136(a).

A shortened statutory period for reply to this final action is set to expire THREE MONTHS from the mailing date of this action. In the event a first reply is filed within TWO MONTHS of the mailing date of this final action and the advisory action is not mailed until after the end of the THREE-MONTH shortened statutory period, then the shortened statutory period will expire on the date the advisory action is mailed, and any

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extension fee pursuant to 37 CFR 1.136(a) will be calculated from the mailing date of the advisory action. In no event, however, will the statutory period for reply expire later than SIX MONTHS from the date of this final action.

8. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Adam R. Giesy whose telephone number is (571) 272-7555. The examiner can normally be reached on 8:00am-4:30pm.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David R. Hudspeth can be reached on (571) 272-7843. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

ARG 9/15/2005

DAVID HUDSPETH
SUPERVISORY PATENT EXAMINER

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